

## **IN THE SPECIFICATION:**

Please amend the specification as follows:

Page 9, amend the paragraph beginning on line 3 to read:

-- Fig.1 shows a ~~In figure 1 shown is the~~ schematic setup of a coating system online compensation system 1. This system comprises a coating source 3, controlled by the coating source supply 5 which typically regulates coating parameters such as power, gasflow, magnet motion etc. This coating source supply 5 itself is regulated by an additional controller 7 which receives signals ~~form~~ from a substrate position detector 13. Substrates 11 are provided on a holder 9 that is rotatable in the direction of the curved arrow in Fig. 1. --

Page 10, amend the paragraph beginning on line 10 to read:

-- Fig. 2 shows a ~~In figure 2 shown is the~~ schematic setup of a coating system 21 with online closed loop correction. This system comprises a coating source 23, controlled by the coating source supply 25 which typically regulates coating parameters such as power, gas flow, magnet motion etc. This coating source 25 itself is regulated by an additional controller 27 which receives signals from a thickness detection system 33. This thickness detection system can be realized by measuring the actual optical transmission and/or reflection characteristic of the substrate 31 on the holder 29, at more than one position on the substrates. A multiple detector system is required for measuring the uniformity at least approximately perpendicular to the direction of motion of the substrates on their hold (curved arrow). --